



Session Title:	[TD1] Plasma Characterization
Session Date:	November 21 (Tue.), 2023
Session Time:	08:50-09:50
Session Room:	Room D (Grand Ballroom 3, 2F)
Session Chair:	Prof. Hae June Lee (Pusan Nat'l Univ., Korea)

[TD1-1] 08:50-09:10

Floating Harmonic Probe Measurement Using Indium Tin Oxide (ITO) Glass for Noninvasive Plasma Diagnostics

Beomjun Seo, Sehun Ahn, and Chinwook chung (Hanyang Univ., Korea)

[TD1-2] 09:10-09:30

Employing Data-Driven Methods for the Evaluation of Plasma Resistance in Ceramics under High-Temperature Conditions

Sung Kyu Jang, Ga In Choi, JunHyeok Jeon, Hyun-Mi Kim, Sun Gil Kim, Seul-Gi Kim, Hyeongkeun Kim, and Woosung Lee (KETI, Korea)

[TD1-3] 09:30-09:50

Development of PI-VM for Monitoring Wafer Etch Uniformity in a VHF-Driven Capacitively Coupled Plasma Equipment

Hyunju Lee, Jae-min Song, Taejun Park, and Gon-Ho Kim (Seoul Nat'l Univ., Korea)